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PATENT ABSTRACTS OF JAPAN

(11)Publication number : 06-184741
 (43)Date of publication of application : 05.07.1994

(51)Int.Cl.

C23C 14/35
 // H01L 21/203

(21)Application number : 04-340757

(71)Applicant : CANON INC

(22)Date of filing : 21.12.1992

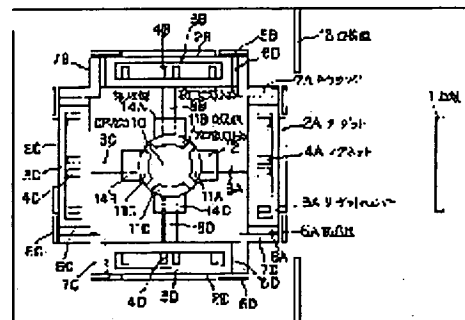
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(54) APPARATUS FOR PRODUCTION OF LAMINATED STRUCTURAL THIN FILM AND
 MOTION INTRODUCING DEVICE

(57)Abstract:

PURPOSE: To prevent the intrusion of the sputtered particles, etc., from the gases released from a vacuum chamber and other targets as impurities into films and to increase the degree of freedom in position control of a substrate in this vacuum chamber.

CONSTITUTION: Plural sputtering sources 2A to 2D mounted with magnetron sputtering electrodes are disposed in parallel around a revolving shaft 10 of a swiveling means and electric power for sputtering is impressed to one of the electrodes. The other electrodes are grounded. Members which can make rotational, linear and oscillatory motions are constituted as the motion introducing device of the vacuum device and a chucking mechanism for converting the above-mentioned linear motion to the holding operation of the substrate 1 is constituted.



LEGAL STATUS

[Date of request for examination]

[Date of sending the examiner's decision of rejection]

[Kind of final disposal of application other than the
 examiner's decision of rejection or application
 converted registration]

[Date of final disposal for application]

[Patent number]

[Date of registration]

[Number of appeal against examiner's decision of
 rejection]

[Date of requesting appeal against examiner's decision]

of rejection]

[Date of extinction of right]

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